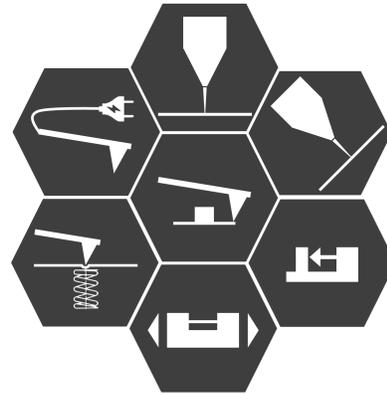


The AFSEM concept



AFSEM correlated microscopy

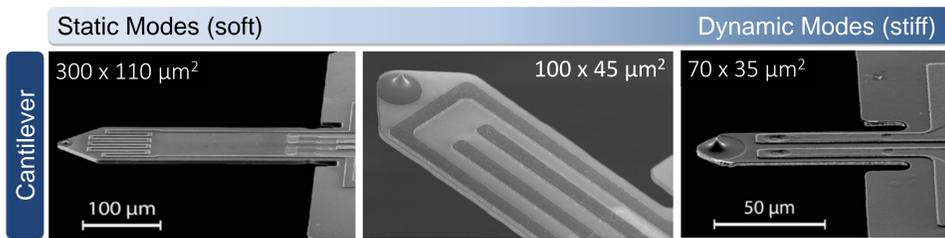
AFSEM is a novel AFM platform specifically designed and developed for integration into other host systems, such as SEM or Dual-beam (SEM/FIB) microscopes. Its open design allows to simultaneously operate SEM/FIB and AFSEM inside the SEM/FIB vacuum chamber.



Main benefits:

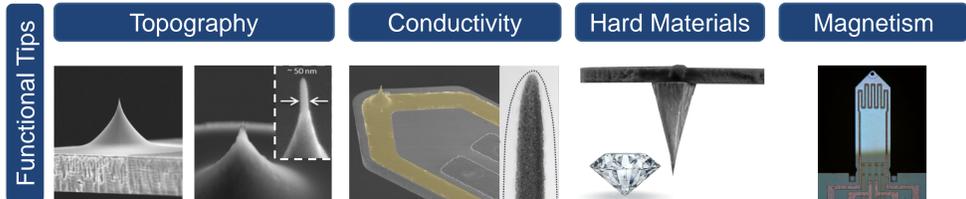
- **Direct 3D information** with sub-nanometer resolution
- **Correlative Microscopy** at highest SEM resolution of exactly the same sample position by SEM/FIB, EDX and AFSEM
- **No air exposure of the sample** during interactive analysis by different methods
- **Nanometer Scale Analysis** before SEM sample contamination
- **Ease of Use** – No AFM laser alignment due to self-sensing cantilever technology
- AFSEM accepts **any Sample** the host system accepts

Self-Sensing Cantilever Technology

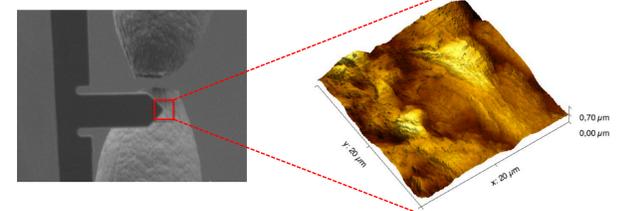
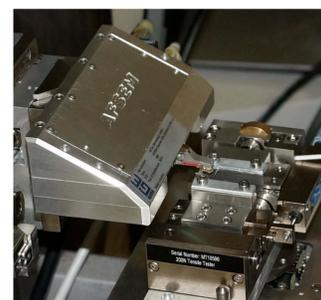


Electrical Noise Level of 0.32 Å for Self-Sensing Cantilever equals Optical Noise Level

M. Dukic, J. D. Adams and G. E. Fantner. *Scientific Reports* 5, 16393 (2015)

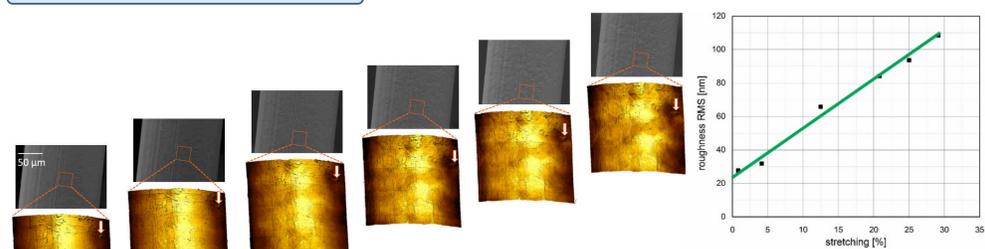


In-Situ Micro-Mechanical Testing



Observe sample changes with SEM, measure details with AFSEM

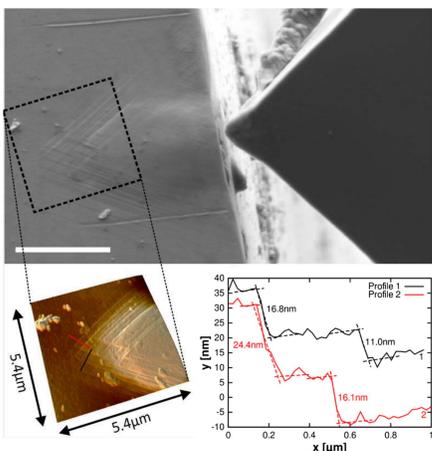
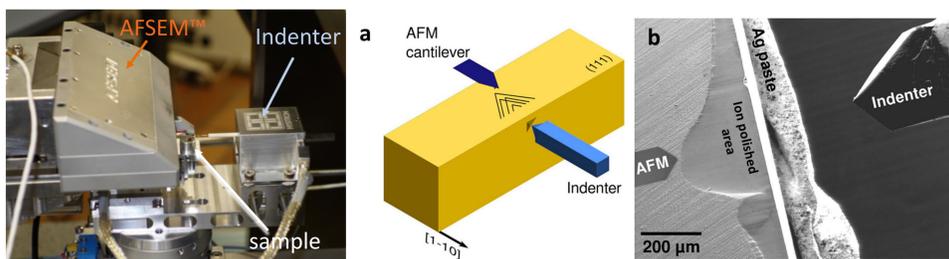
Combine SEM, tensile stage and AFSEM



Correlative roughness analysis under load inside the SEM

Correlative Nano-indentation Analysis

Combine SEM, nano-indentor and AFSEM for correlative *in-situ* experiments

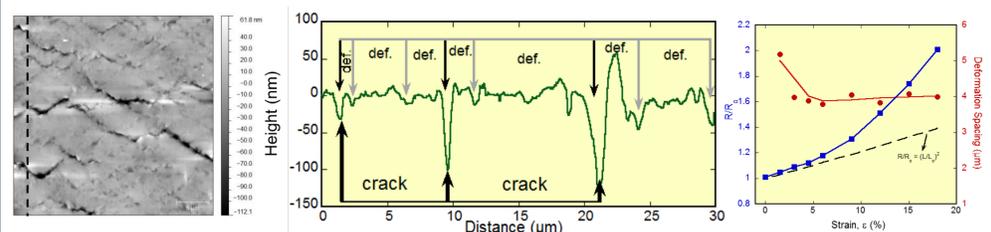


- Investigate evolution of slip-step dynamics with sub-nanometer resolution
- Analyze your sample before SEM contamination or oxidation effects
- Quantify the number of emitted dislocations exactly at the area of interest

J. Kreith et al., *Rev. Sci. Instrum.* 88, 053704 (2017)

Mechanical Testing of Flexible Electronics

Combine SEM, AFM and *in-situ* 4-point-probe measurements to study flexible electronics during straining



Measure *in-situ* 3D-topography AND conductivity

